

U.S. Patent Application Serial No. 10/829,018
Reply to Office Action dated July 12, 2006

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In the Abstract

Please replace the Abstract with the following amended paragraph:

Disclosed herein is a wafer carrier locking device. The wafer carrier locking device includes a wafer carrier seated thereon a plurality of wafers. A main equipment executes a semiconductor manufacturing process, ~~which is a wafer cleaning process, a wafer etching process, etc., when the wafers seated on the wafer carrier are fed to the main equipment by a multi-joint robot.~~ An auxiliary equipment includes a carrier sensor to detect a seated state of the wafer carrier relative to a base member, a wafer sensor to detect a number and positions of the wafers seated on the wafer carrier, ~~when the wafer carrier is seated on the base member,~~ and the base member having a plate shape. ~~In this case, a plurality of positioning blocks are provided at predetermined positions of the base member to allow the wafer carrier to be seated at a desired position on the base member.~~ A locking unit is provided at a front portion of the base member to prevent the wafer carrier from being undesirably moved, ~~when the wafer carrier is seated on the base member during the semiconductor manufacturing process of the main equipment.~~ The wafer locking device of this invention prevents a wafer from being broken or damaged due to carelessness of a worker, and prevents a waste of resources due to the damaged wafer, and enhances productivity.